

CDLD-11S06 Tylan General 0-10Torr 0-10VDC Capacitance Diaphragm Gauge Datasheet



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Category: Process Sensors

Price: **\$1,628.57**

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Product Description

The Tylan General CDLD-11S06 is a high-precision capacitance diaphragm manometer featuring a 0 to 10 Torr full scale measurement range and a 0 to 10 VDC linear analog output. This unheated vacuum transducer utilizes an all-welded Inconel and 316L stainless steel sensor assembly to ensure chemical compatibility with corrosive process gases. The internal sensing mechanism consists of a tensioned metal diaphragm that detects pressure-induced capacitance changes, providing a fast 10 ms response time and excellent zero stability. The unit is powered by a dual +/- 15 VDC supply and is typically equipped with standard vacuum interfaces such as KF-16 or VCR fittings for seamless integration into high-vacuum manifolds.

CDLD-11S06 Specifications

Model Number: CDLD-11S06

Brand: Tylan General (Millipore)

Product Category: Capacitance Diaphragm Gauge (CDG)

Pressure Range: 0 to 10 Torr

Output Signal: 0 to 10 VDC

Input Power: +/- 15 VDC (+/- 5%)

Input Current: 35 mA minimum

Response Time: 10 ms

Accuracy: 0.5% of reading (standard for CDL series)

Overpressure Limit: 17 PSIA or 125% of full scale

Operating Temperature: 5 to 45 °C

Temperature Coefficient Zero: 0.005% F.S. per °C

Temperature Coefficient Span: 0.02% of reading per °C

Wetted Materials: Inconel and 316L Stainless Steel

Internal Volume: 17 cc

Fittings: KF-16, 8 VCR female, or 8 VCO female (model dependent)

Connector Type: 15-pin sub-D or Removable terminal strip

Origin: United States

CDLD-11S06 Applications

Primary applications include integration into semiconductor chemical vapor deposition (CVD) systems, physical vapor deposition (PVD) sputtering tools, and plasma etching chambers for precise process pressure control. Deployed within laboratory vacuum lines, mass spectrometer inlet systems, and industrial thin-film coating equipment to monitor sub-atmospheric gas environments.

Supplemental Images

